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AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 3749
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Group Art Unit: 3749

Confirmation No.: 2926

Examiner: Kathryn S. O Malley

Filed: March 18, 2002

For: CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

AMENDMENT UNDER 37 C.F.R. § 1.116

MAIL STOP AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Responsive to the outstanding Final Office Action of May 17, 2005, please amend the above-identified application as follows on the accompanying pages.

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